

INTRODUCTION

Microfluidics, as a crucial technology of recent years, enables numerous applications for Point-of-Care-Testing such as Lab-on-Chip-Systems (LOC) or Micro-Total-Analysis-Systems (μ TAS). Especially the implementation of dielectrophoresis (DEP) in microfluidic chips has evolved to a subtle method for precise manipulation of cells, molecules or particles [1, 2]. Objective of the present analysis is the optimization of DEP due to a well-suited arrangement of copper electrodes within the chip system. Furthermore, the context between an applied voltage, the resulting strength of the electric DC-field as well as the deflection and acceleration of zirconium oxide particles is evaluated.

PRINCIPLE OF DIELECTROPHORESIS (DEP)

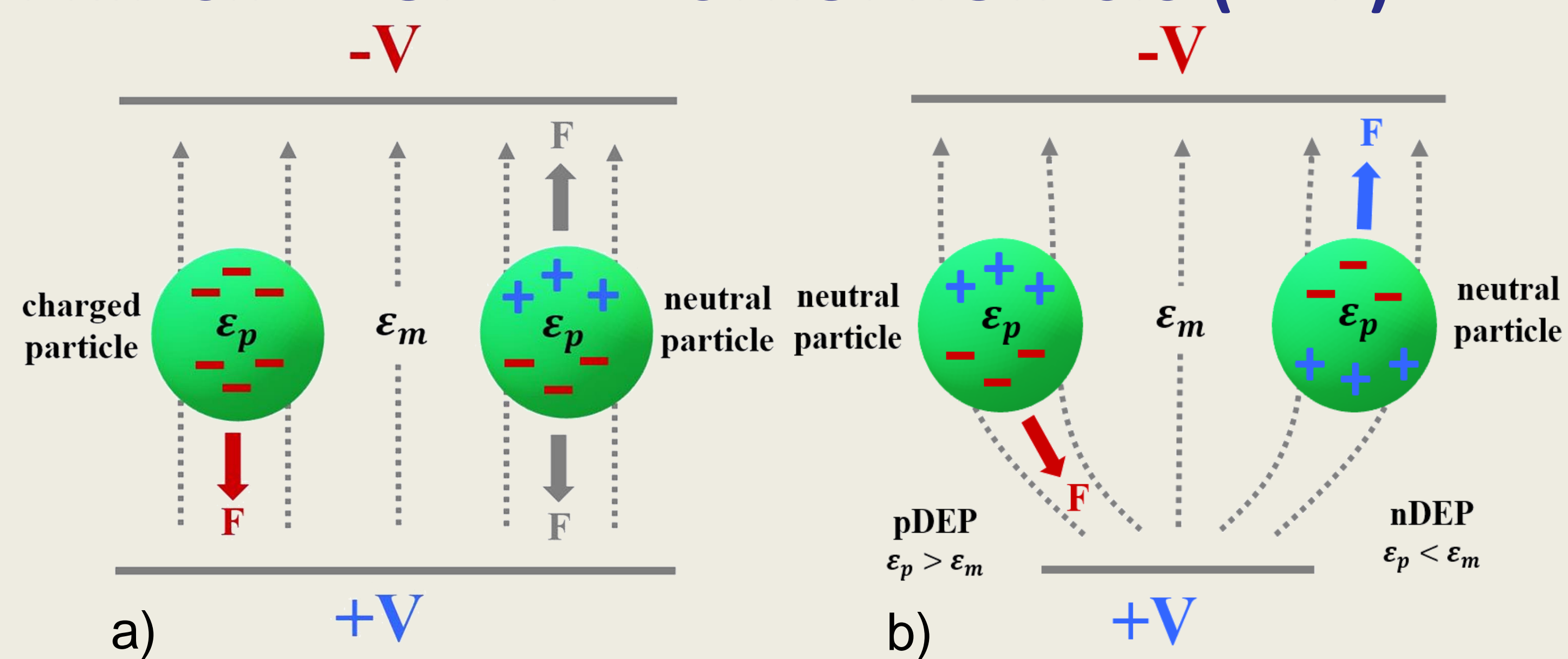
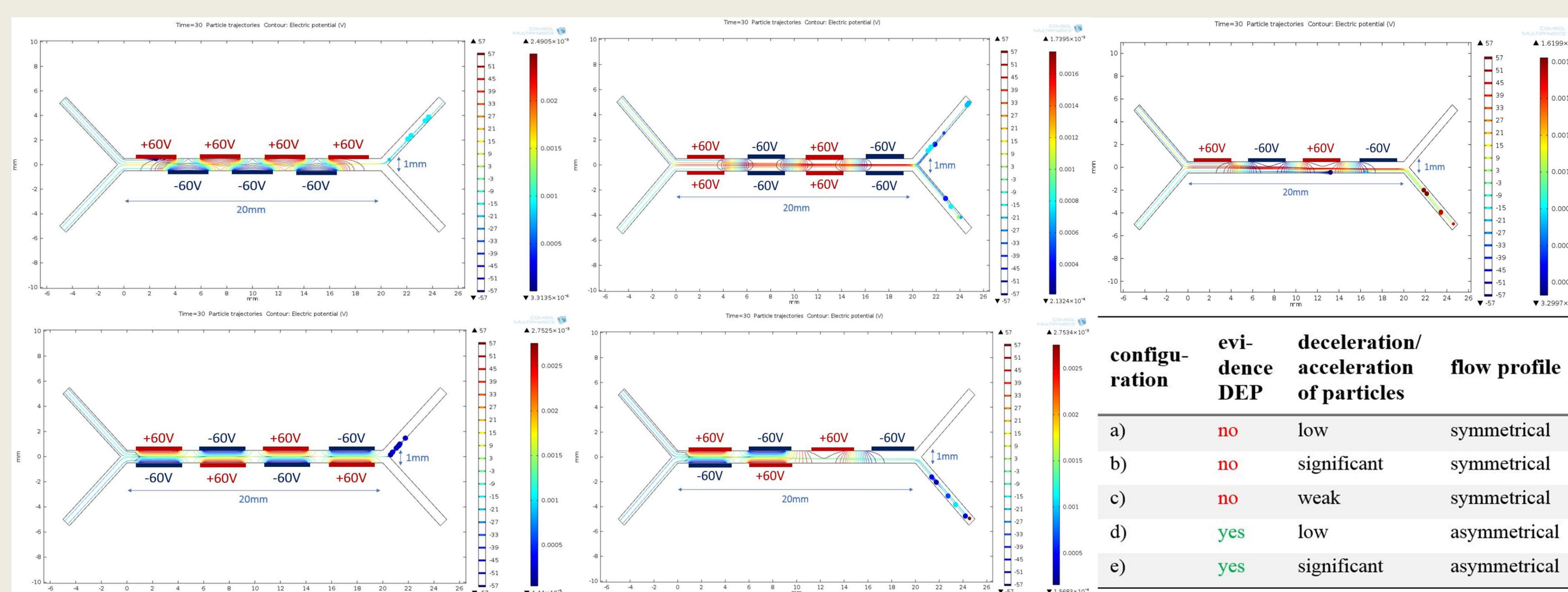


Figure 2. a) Uniform electric field; b) DEP in a non-uniform electric field: positive DEP (left) and negative DEP (right).

INVESTIGATION OF VARIOUS ELECTRODE CONFIGURATIONS



- ▶ COMSOL Multiphysics[®] (Electrostatics, Laminar Flow).
- ▶ Use of Particle Tracing Module.
- ▶ Particle diameters: 30-60 μ m.
- ▶ Biased configuration generates distinct DEP.
- ▶ Applied voltage: threshold at least ± 50 V.

Figure 3. DEP: Electrode configurations.

Table 1. Summary of the simulation results.

CONCLUSIONS

A COMSOL Multiphysics[®] model of a microfluidic chip system for DEP manipulation of colloids was successfully established. In this context, an optimized arrangement of copper electrodes to generate a mandatory non-uniform electric DC-field was found as well as a threshold, which must be exceeded to achieve reliable and reproducible results.

MICROFLUIDIC CHIP SYSTEM

- ▶ Additive manufactured via MultiJet Modeling.
- ▶ Integrated Luer-Lock system for simple handling:

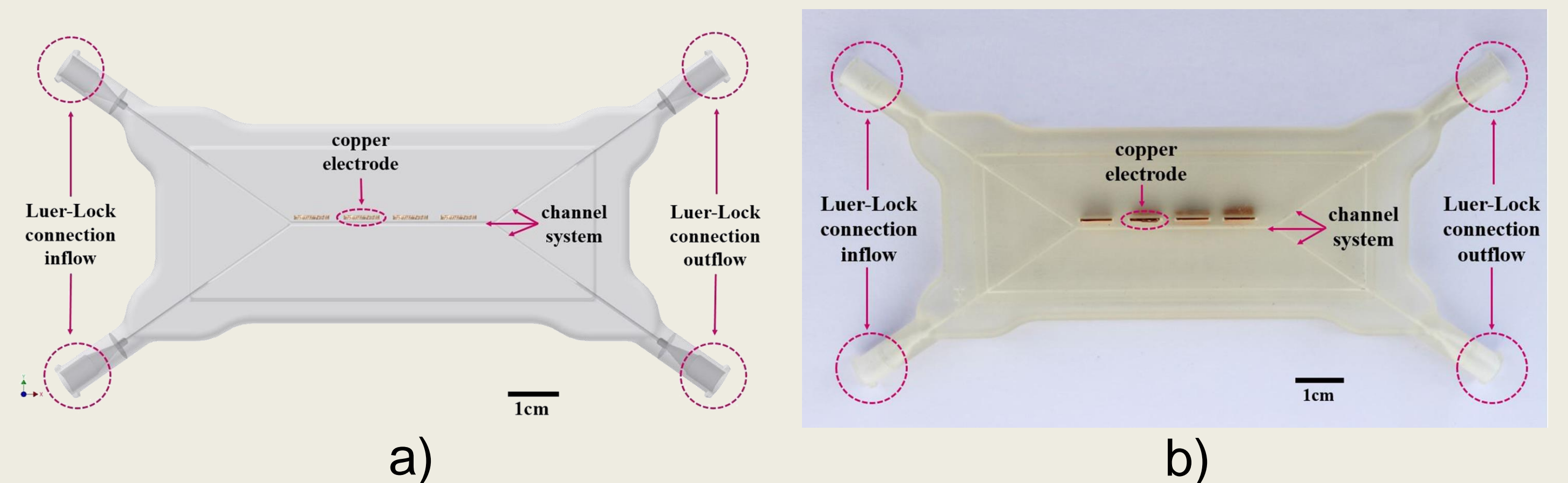


Figure 1. a) CAD-model of the microfluidic chip system; b) 3D-printed chip system with integrated electrodes for realization of DEP.

- ▶ DEP is part of electrokinetic phenomena.
- ▶ Movement of particles subjected to a non-uniform electric field.
- ▶ Interaction between dipole of the particle and spatial gradient of the electric field.
- ▶ Generated dielectrophoretic force [3]:

$$F_{DEP} = 2\pi r^3 \epsilon_0 \epsilon_m \Re[f_{CM}(\omega)] \nabla E_{rms}^2 \quad (1)$$
- ▶ Clausius-Mossotti-Factor reflects the extent of particle polarization in DC-fields via [4]:

$$f_{CM}(\sigma_p, \sigma_m) = \frac{\sigma_p - \sigma_m}{\sigma_p - 2\sigma_m} \quad (2)$$
- ▶ Two principles of DEP: positive dielectrophoresis (pDEP) and negative dielectrophoresis (nDEP).

REFERENCES

- [1] P. K. Wong et al., *Electrokinetics in Micro Devices for Biotechnology Applications*, IEEE/ASME Transactions on Mechatronics, Vol. 9, pp. 366-376 (2004).
- [2] H. A. Pohl, *Dielectrophoresis: The Behavior of Neutral Matter in Nonuniform Electric Fields*. Cambridge and New York (1978).
- [3] B. Cetin & D. Li, *Dielectrophoresis in microfluidics technology*. Electrophoresis, Vol. 32, pp. 2410-2427 (2011).
- [4] A. Mortadi et al., *Studies of the Clausius-Mossotti-Factor*. Journal of Physical Studies, Vol. 20, pp. 4001-4004 (2016).